



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Pablo I. Rovira
Assignee: Nanometrics Incorporated
Title: Optical Metrology System with Combined Interferometer and Ellipsometer
Serial No.: 10/016,943 Filing Date: December 13, 2001
Examiner: Samual A. Turner Group Art Unit: 2877
Docket No.: NAN051 US Confirmation No.: 7400

Santa Clara, California
May 5, 2004

Mail Stop Issue Fee
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT PURSUANT TO 37 C.F.R. §1.312

Dear Sir:

This Amendment is filed pursuant to 37 C.F.R. §1.312 and is filed before or with the payment of the issue fee. Please enter the following amendment before issuing the above-referenced application to issue.

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